

Amendments to the Claims

This listing of claims will replace all prior versions and listing of claims. Added material is underlined and deleted material is shown in strike through, to show the changes made.

14 1-16. (Canceled)

1 17. (Currently Amended) A system for supercritical processing of an object, the system
2 comprising:

- 3 a. means for performing a supercritical process;
4 b. means for measuring a pump performance parameter; and
5 c. means for adjusting operation of a pump to control a fluid flow in response
6 to the pump performance parameter,

7 wherein the means for performing a supercritical process comprises
8 a processing chamber and
9 means for circulating at least one of a gaseous, liquid, supercritical and near-
10 supercritical fluid within the processing chamber.

1 18. (Previously Amended) The system of claim 17 wherein the object is a semiconductor
2 wafer for forming integrated circuits.

1 19. (Canceled)

1 20. (Currently Amended) The system of claim 17 ~~19~~ wherein the means for circulating is a
2 means for circulating a fluid comprising carbon dioxide.

1 21. (Previously Amended) The system of claim 20 wherein at least one of solvents, co-
2 solvents and surfactants are contained in the carbon dioxide.

1 22. (Previously Amended) The system of claim 17 wherein the pump performance parameter
2 comprises at least one of a pump speed, voltage, electric current, and electric power.

1 23. (Previously Amended) The system of claim 17 further comprising means for delivering
2 the fluid flow to the means for performing a supercritical process.

24-28. (Canceled)